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PATENT

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant : Kamal Kisho Goundar  
Appl. No. : 10/616,163  
Filed : July 9, 2003  
For : METHOD OF FORMING  
SILICON CARBIDE FILMS  
Examiner : Monica D Harrison  
Group Art Unit : ~~2829~~ 2813

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

October 18, 2005

(Date)

  
Katsuhiro Arai, Reg. No. 43,315

**RESPONSE TO FINAL OFFICE ACTION**

**Mail Stop AF**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

This is in response to the Office Action mailed July 27, 2005. Please reconsider the present application in light of the following comments.

**Remarks/Arguments** begin on page 2 of this paper.